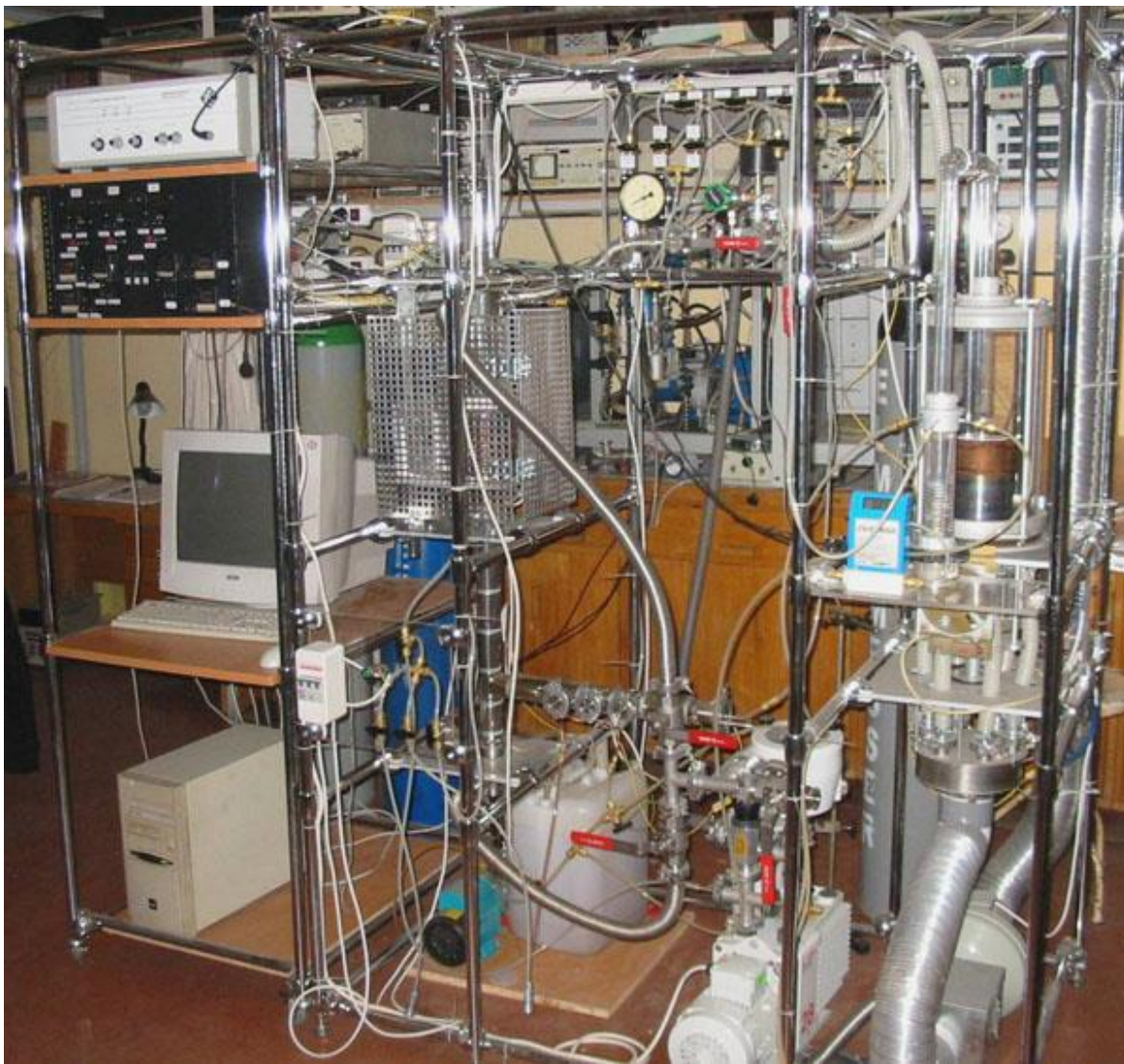




A system of two Pulsed Injection MOCVD reactors for oxide depositions

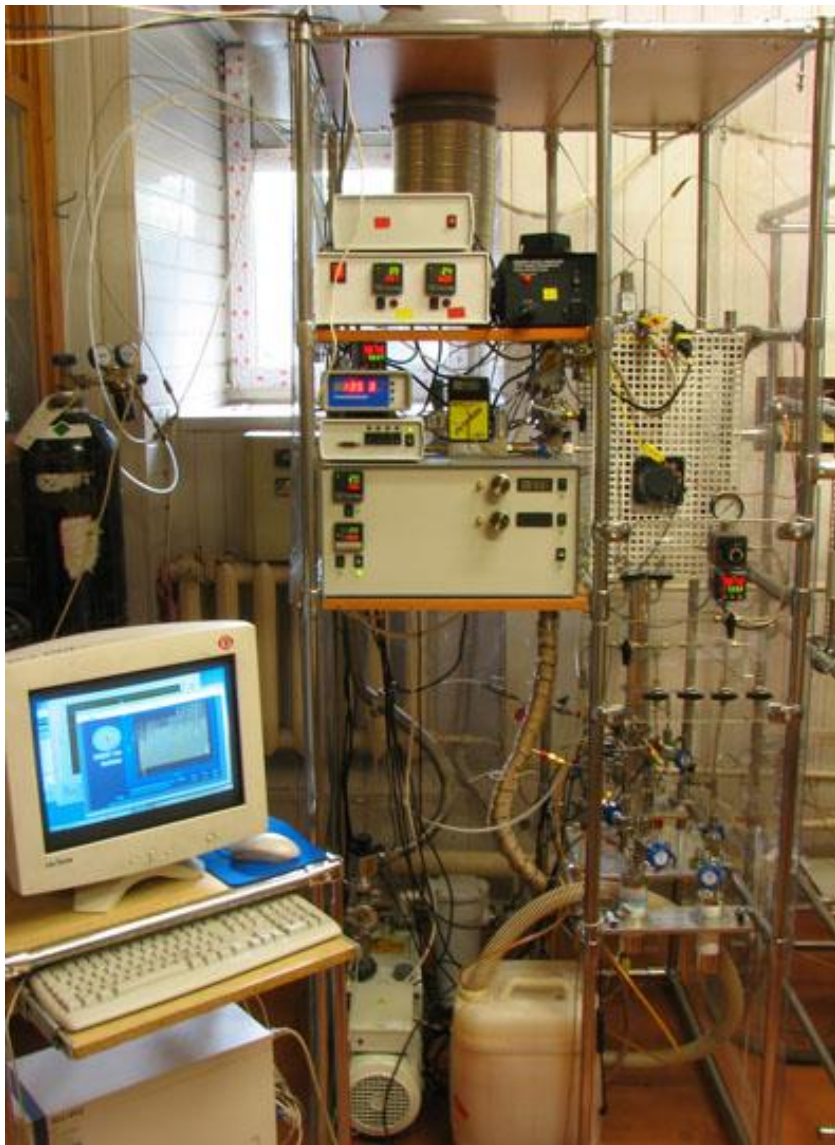




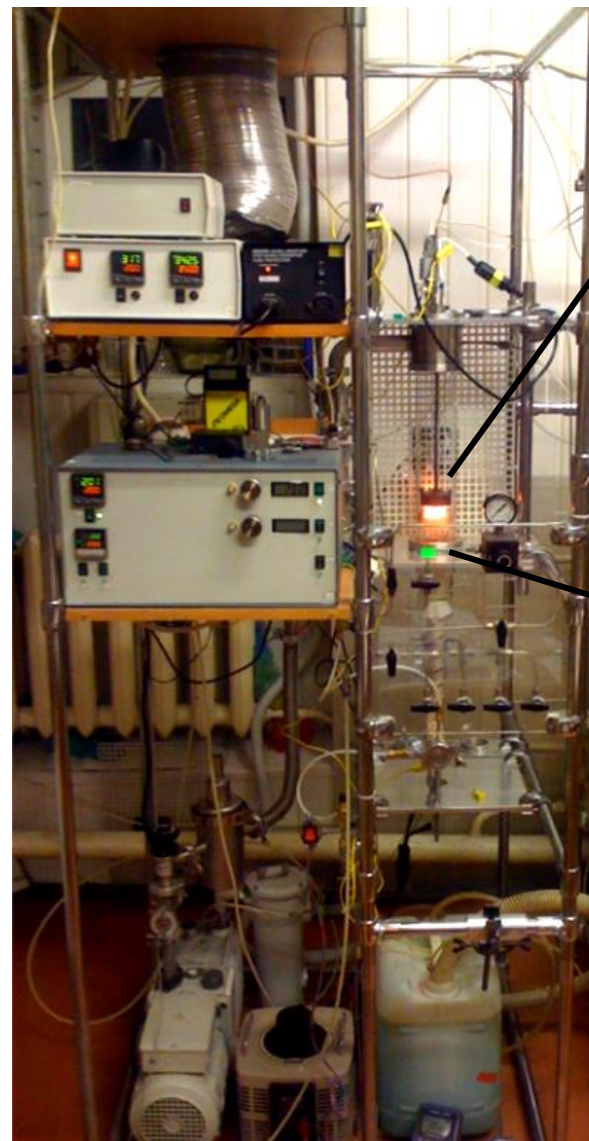
Mini aerosol –assisted  
atmospheric pressure  
MOCVD reactor  
(aerosol-pyrolysis reactor)

A system of two reactors: left – Pulsed Injection MOCVD reactor, right –aerosol-assisted atmospheric pressure MOCVD reactor for deposition on large area substrates.





Combined Pulsed Injection MOCVD - Hot-Wire CVD reactor (used for the growth of chalcogenide materials – GeTe and Ge-Sb-Te)



Hot-Wire MOCVD reactor for depositions of oxides